## Supporting Information For

## Solution-Synthesized High-Mobility Tellurium Nanoflakes for Short-Wave Infrared Photodetectors

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**Figure S1.** (a) Temperature-dependent  $I_d$ - $V_g$  characteristics of a 12 nm thick Te nanoflake using a 50 nm thick back gate SiO<sub>2</sub>, measured at a low  $V_d$  of -10 mV. (b) Temperature-dependent  $I_d$ - $V_g$ characteristics of a 14.5 nm thick Te nanoflake using a 50 nm thick back gate SiO<sub>2</sub>, measured at a low  $V_d$  of -10 mV. (c) Temperature-dependent I<sub>d</sub>- $V_g$  characteristics of a 21.6 nm thick Te nanoflake using a 50 nm thick back gate SiO<sub>2</sub>, measured at a low  $V_d$  of -10 mV.



**Figure S2.** Tauc plots used to extract the indirect bandgap and direct bandgap of the quasi-2D nanoflakes.



**Figure S3.** Reflection spectra of Te nanoflakes with different thicknesses on Au substrate. Inset shows a scheme of the optical path used in the measurement.



Figure S4. Polarization-resolved photoresponse of a quasi-2D Te photoconductor on a Si / 50 nm thick  $SiO_2$  substrate. It is important to note that a thicker sample was used here to improve the measurement resolution near the indirect gap.



**Figure S5.** Reflection spectra taken on Te nanoflakes deposited on an  $Al_2O_3/Au$  substrate with varying  $Al_2O_3$  spacer thicknesses.